

The Meaglow 50 series Hollow Cathode Plasma Source



The **NEXT**

GENERA

Mounted on an NW50 (KF50) vacuum flange, the 50 series Hollow Cathode source is capable of being housed in an NW50 nipple. Widely used for ALD, it features:

- 300 or 600 Watt RF or DC operation.
- 316 Stainless steel cathode construction (other materials on demand) water cooled.
- Wide range of gas usage.
- Low oxygen contamination (no dielectric windows).
- Low cost.
- High electron density similar to inductively coupled and microwave plasma sources.

• Wide range of operating pressures (eg. from 100 mTorr to > 5 Torr). A low pressure option is also available.

- Low plasma damage.
- Customised solutions available.

Related Papers:

- K. S. A. Butcher, B. W. Kemp, I. B. Hristov, P. Terziyska, P. W. Binsted and D. Alexandrov, Japanese Journal of Applied Physics 51 (2012) 01AF02.
- C. Ozgit-Akgun, E. Goldenberg, A. Kemal Okyay and N. Biyikili, Journal of Materials Chemisty C 2 (2014) 2123.

For more information on Meaglow Ltd or its hollow cathode plasma sources, visit our website <u>www.meaglow.com</u> or contact us at <u>info@meaglow.com</u>.

Meaglow Ltd manufactures and sells crystal growth research reactors and supplies hollow cathode plasma sources for advanced semiconductor applications.

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The Meaglow 50 series Hollow Cathode Plasma Source specifications:

- NW50 (KF50) vacuum connection.
- NW50 (KF50) nipple housing on request.
- 300 or 600 Watt maximum applied power.
- DC or 13.56 MHz RF operation.
- N, HN or 7/16 DIN input voltage connectors, others on request.
- Male or female VCR gas input.
- Water cooling, 1-3 litres/min room temperature water (distilled or deionised preferable). Swagelok connections.

The **NEXT**

NERA

• Integrated matching box on request.

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- 316 stainless is standard, but other cathode materials on request.
- Operation from 100 mTorr to > 5 Torr (low pressure option available).
- Gases to date: NH₃, N₂, H₂, Ar, O, NO, others possible (Cl and F) depending on material compatibility.

• RF generator, matching network and matching network controller supplied on request. Will advise for modification of existing equipment.

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